

# Agilent 1260 Infinity Multiple Wavelength Detector

# Features, Technical Details, Specifications and Ordering Details

### Real multiple wavelength detection for ultrafast LC

The Agilent 1260 Infinity Multiple Wavelength detector (MWD) provides simultaneous detection of up to 8 compound specific wavelengths for optimum selectivity over a wavelength range from 190 nm to 950 nm. The improved diode array design offers very low detector noise (< $\pm$  7 µAU) for precise quantification of trace levels, regardless of how many signals are recorded. High-speed UV detection with up to 80 Hz data rates keeping pace with the analysis speed of fast LC.

#### **Features**

- Simultaneous acquisition of up to 8 compound-specific wavelengths for increased sensitivity and selectivity.
- Low noise front-end electronics and the patented flow cell design delivers very low detection limits resulting from minimized short-term noise (<  $\pm$  7 µAU).
- Up to 100% resolution gain in fast LC by 80 Hz data acquisition rate.
- Electronic temperature control (ETC) maximum baseline stability and practical sensitivity under fluctuating ambient temperature and humidity conditions.
- Wide linear range for reliable, simultaneous quantification of primary compounds, by-products and impurities.
- Programmable slit (1 to 16 nm) for rapid optimization of sensitivity and linearity.
- New data recovery card (DRC) and radio frequency identification (RFID) technology provide new levels of data security and traceability.
- Automatic wavelength verification by built-in holmium oxide filter.
- Range of 9 analytical and preparative flow cells provide maximum application flexibility.
- Extensive diagnostics, error detection and display with Agilent 1200 Series Instant Pilot controller and Agilent Lab Advisor software.



### Technical Details – Agilent 1260 Infinity Multiple Wavelength Detector

# Diode-array design for uncompromised sensitivity

With conventional scanning UV-detectors the sensitivity is decreasing with the numbers of acquired signals. The 1260 Infinity multiple wavelength detector is based on an improved diode array design which offers the same high sensitivity for both single and multiple wavelength detection.





#### Multiple wavelength detection for increased sensitivity and selectivity

The 1260 Infinity multiple wavelength detector allows the simultaneous acquisition of up to 8 compound-specific wavelengths. This ensures optimum detection conditions in terms of selectivity and sensitivity especially for closely eluting compounds.



Sensitive quantitation of active compounds and impurities in a single run without wavelength switching.

#### Maximum baseline stability

The electronic temperature control reduces baseline wander by more than a factor of 20. Even under the harshest ambient conditions, the baseline of the Agilent 1260 Infinity MWD remains constant within 30 IAU/°C.



Baseline wander with electronic temperature control turned on and off.

#### 80 Hz data rates for fast LC

Fast LC analyses can generates sharp and narrow peaks with peak widths smaller than 1 second. The 1260 Infinity multiple wavelength detectors offer multiple wavelength detection of 8 signals at 80 Hz data rate, keeping pace with the analysis speed of fast LC.





### New level of data security and traceability

"Data-never-lost-insurance" with built-in data recovery card (DRC) prevents data losses in the event of communication breakdowns between instrument and PC by automatically buffering raw and metadata on an embedded memory card. Radio frequency identification (RFID) tags for all flow cells and UV lamp provide highest levels of data traceability by recording parameters, such as product and serial number, production date, cell dimensions, lamp usage, and the date of the last successful cell or lamp test.



Data recovery card offers "data never lost" insurance and prevents data I osses by buffering raw and metadta

### Specifications – Agilent 1260 Infinity Multiple Wavelength Detectors

Specifications: 1280 Infinity Multiple Wavelength Detector (61395)           Detector type         1024 element diode array           Detector type         0124 element diode array           Resting         8           Maximu sampling rate         80 Hz           Short-term noise         < ± 0.7 x 10 <sup>4</sup> All /16 zl 554 nm           Drift         < 0.9 x 103 All /16 zl 554 nm           Linearity         > 2.0 All (5 54) at 255 nm           Wavelength accuracy         1 nm, self-calibration with dueterum lines. Verification with holmium exide filter,           Didd         < 1 nm, self-calibration with dueterum lines. Verification with holmium exide filter,           Didd widdh         < 1 nm, self-calibration with dueterum lines. Verification with holmium exide filter,           Didd widdh         < 1 nm, self-calibration with dueterum lines. Verification with holmium exide filter,           Didd widdh         < 1 nm           Wavelength bunching         Programmable, 1 - 400 nm, in steps of 1 nm           Struit verifiers         Struit verifiers	Specificatione: 1260 Infinity Multiple Wayslangth Detector (C126EC)			
Lipt source         Deuterium and tungsten           Number of signals         8           Maximu sampling rate         80 Hz           Short-term noise         < 10 2 x 10 3 AU/nr at 254 nm           Construction         > 20 AU (5 %) at 205 nm           Unearity         > 20 AU (5 %) at 205 nm           Wavelength range         190 950 nm           Wavelength accuracy         4 1 nm, solf-calibration with douterium lines. Verification with holmium oxide filter,           Didd         < 1 nm, solf-calibration with douterium lines. Verification with holmium oxide filter,           Wavelength bunching         Programmable, 1 - 400 nm, in staps of 1 nm           Flow cells         Standard Sali, Volume, 10 nm, cell path length, 120 bar (1740 psi) pressure maximum           Semi-inero Sput, volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Semi-inero Sult, volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Micro Sult, volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Semi-inero Sulter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Sult         Sulter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Sult         Sulter volume, 6-mm cell path length, 120 bar (7140 psi) pressure maximum           Sulter volume, 6-mm cell path length, 120 bar (7140 psi) pressure maximum           Sulter volume, 6-mm cell path length, 120 bar (7140				
Number of signals         8           Maximum sampling rate         80 Hz           Short-term noise         < ± 0.7 10 <sup>6</sup> AU at 254/4 nm and at 750 nm, TC 2 soc. cell           Drift         < 0.9 x 10 <sup>3</sup> AU/r at 254 nm           Linearity         > 20 AU (5%) at 256/5 nm           Wavelength accuracy         ± 1 nm, solf-calibration with douterium lines. Verification with holmium oxide filter.           Sitt with         Programmable: 1.2, 4, 8, 16 nm           Diode width         < 1 nm           Vavelength bunching         Programmable: 1.2, 4, 8, 16 nm           Biode vidth         Programmable: 1.2, 4, 00 nm, in steps of 1 nm           Flow cells         Standard           Tay, Lvolume, 6 mm cell path length, 120 bar (1740 psi) pressure maximum           Semi-micro         5µL volume, 6 mm cell path length, 120 bar (1740 psi) pressure maximum           Semi-micro         5µL volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Semi-micro         5µL volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Nano         Semi-micro           Semi-micro         5µL volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Nano         Semi-micro           Semi-micro         5µL volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum           Nano         Semi-micro <th></th> <th colspan="2">· ·</th>		· ·		
Name         80 Hz           Short-term noise         < ± 0.7 x 10 <sup>5</sup> AU /t rat 254 / a m and at 750 nm, TC 2 sec. cell           Drift         < 0.9 x 10.3 AU /t rat 254 nm           Linearity         > 2.0 AU (5 %) at 256 nm           Wavelength range         190-950 nm           Wavelength accuracy         14 nm, self-calibration with deuterium lines. Verification with holmium oxide filter,           Sitt width         Programmable: 1.2 4, 8.16 nm           Dide width         < 1 nm           Wavelength bunching         Programmable: 1.400 nm, in steps of 1 nm           Flow cells         Standard           13.1 volume, 6 mm cell path length, 120 bar (1740 psi) pressure maximum           Semi-nano         Semi-nano           S00 - anoliter volume, 6 -mm cell path length, 120 bar (1740 psi) pressure maximum           Marce         Spit. volume, 3 -mm cell path length, 50 bar (725 psi) pressure maximum           Marce         B0-anoliter volume, 10 -mm cell path length, 50 bar (725 psi) pressure maximum           Marce         B0-anoliter volume, 10 -mm cell path length, 50 bar (725 psi) pressure maximum           Marce         B0-anoliter volume, 10 -mm cell path length, 400 bar (5802 psi) pressure maximum           Marce         B0-anoliter volume, 10 -mm cell path length, 400 bar (5802 psi) pressure maximum           Marce         B0-anoliter volume, 10 -mm cell path length,	-			
Short-term< ± 0.7 x 10 s AU at 254/4 nm and at 750 nm. TC 2 sec. cell	Ū			
Drift         < 0.9 x 10 <sup>3</sup> AU/hr at 254 nm           Linearity         > 2.0 AU (5 %) at 255 nm           Wavelength range         190-950 nm           Wavelength accuracy         £ 1 nm. self-calibration with deuterium lines. Verification with holmium oxide filter,           Slit width         Programmable 1. 2, 4, 8, 16 nm           Diode width         < 1 nm           Wavelength bunching         Programmable, 1. 400 nm, in steps of 1 nm           Flow cells         Standard 13 µL volume, 0 mm cell path length, 120 bar (1740 psi) pressure maximum           Smimicro 5 µL volume, 0-mm cell path length, 120 bar (1740 psi) pressure maximum         Smimicro 5 µL volume, 0-mm cell path length, 120 bar (725 psi) pressure maximum           Micro 5 µL volume, 0-mm cell path length, 50 bar (725 psi) pressure maximum         Smimicro 5 µL volume, 0-mm cell path length, 50 bar (725 psi) pressure maximum           Nano         80 nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum         Nano           Nano         80 ranoliter volume, 0 for mm cell path length, 120 bar (1740 psi) pressure maximum         Nano           Nano         80 ranoliter volume, 0 for mc cell path length, 120 bar (1740 psi) pressure maximum         Nano           Nano         80 ranoliter volume, 0 for mc cell path length, 120 bar (1740 psi) pressure maximum         Nano           Nano         90 rano cell path length, 120 bar (211 psi) pressure maximum         Nap				
Linearity> 20 AU (5 %) at 265 nmWavelength range180-950 nmWavelength accuracy± 1 nm, soff calibration with dustrium lines. Verification with holmium oxide filter.Sitt withProgrammable 1, 2. 4. 8, 16 nmDiode with< 1 nmWavelength bunchingProgrammable 1, 4.00 nm, in steps of 1 nmFlow cellsSandard 13, th volume, 10 nm-cell path length, 120 bar (1740 psi) pressure maximum Seriminor 5-jul volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum Seriminor 5-jul volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum Narco 80-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum Nano 80-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum Nano 80-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum Nano 80-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum Preparative 3 mm 03-mm cell path length, 20 bar (201 psi) pressure maximum Preparative 0.66 mm 03-mm cell path length, 20 bar (201 psi) pressure maximum Preparative 0.66 mm 				
Wavelength range         190.950 nm           Wavelength accuracy         ± 1 nm, self-calibration with deuterium lines. Verification with holmium oxide filter,           Slit width         Programmable: 1. 2, 4, 8, 16 nm           Diode width         < 1 nm           Wavelength hunching         Programmable, 1 -400 nm, in steps of 1 nm           Flow cells         Standard           13-jt volume, 10 nm-cell path length, 120 bar (1740 psi) pressure maximum           Semi-micro         S-jt/, volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum           Semi-mano         500-nanoliter volume, 10-mm cell path length, 120 bar (1740 psi) pressure maximum           Bit-nano         500-nanoliter volume, 5-mm cell path length, 50 bar (725 psi) pressure maximum           Bit-nanoliter volume, 5-mm cell path length, 50 bar (725 psi) pressure maximum         Nano           Bit-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Nano           Bit-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Nano           Bit-nanoliter volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Nano           Bit-nanoliter volume, 6-mm cell path length, 50 bar (25 psi) pressure maximum         Nano           Bit-nanoliter volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Nano           Bit-macell path length, 120 bar (251 psi) pressure maximum				
Wavelength accuracy       ± 1 nm, self-calibration with deuterium lines. Verification with holmium oxide filter,         Site width       Programmable: 1, 2, 4, 8, 16 nm         Diode width       < 1 nm         Wavelength bunching       Programmable, 1 - 400 nm, in steps of 1 nm         Flow cells       Standard         13-jtl, volume, 10 nm-cell path length, 120 bar (1740 psi) pressure maximum         Semi-mico       5-jtl, volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Strico       2-jtl, volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Nano       80-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum         Nano       80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         High Pressure (If SFG)       1.7-yit, volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Preparative 3 nm       3-mm cell path length, 120 bar (1740 psi) pressure maximum         Preparative 3 nm       3-mm cell path length, 120 bar (251 psi) pressure maximum, quartz         Preparative 0.6 mm       0.96-mm cell path length, 20 bar (251 psi) pressure maximum, quartz         Preparative 0.6 mm       0.96-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Communications       LAN, Controller-area network (CAN), RS-232C, APG Remote: ready, Start, stop and shut-down signals.         GLP features       Data recovery ca	Linearity			
Slit width       Programmable: 1, 2, 4, 8, 6 nm         Diode width       < 1 nm         Wavelength bunching       Programmable, 1 - 400 nm, in steps of 1 nm         Flow cells       Standard         Standard       3-pt, volume, 10 mm-cell path length, 120 bar (1740 psi) pressure maximum         Semi-inco       5-pt, volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Semi-nano       500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum         Smi-nano       500-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Nane       80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Nane       30-nanoliter volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Preparative 3 mm       3-amn cell path length, 120 bar (1740 psi) pressure maximum         Preparative 3 mm       3-amm cell path length, 120 bar (291 psi) pressure maximum, quartz         Time programmable       Wavelength, polarity, peak width, lamp bandwidth, autobalance, wavelength range, threshold, spectra storage mode.         Analog output       Recorder/integrator: 100 mV or 1 V, 2 outputs.         Communications       LAN, Controller-area network (CAN), RS 232C, APG Remote: ready. Start, stop and shut-down signals.         BLP features       Data recovery card to prevent data losses. RFID for electronics records of flow cell and UV lamp conditions (path length, autobe	Wavelength range			
Dide width       <1 nm         Wavelength bunching       Programmable, 1 - 400 nm, in steps of 1 nm         Flow cells       Standard         13-µL, volume, 10 nm-cell path length, 120 bar (1740 psi) pressure maximum         Semi-micro         Semi-micro         SpL, volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Micro         2-µL, volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Semi-naon         500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum         Nane         80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         Preparative 3 nm         3-mm cell path length, 120 bar (1740 psi) pressure maximum         Preparative 3 nm         3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Preparative 3 nm         3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Preparative 3 nm         3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Preparative 3 nm         3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Preparative 3 nm         3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Preparative 3 nm         3-mm cell path length, 85 2320, APG Remote: ready, Start, stop	Wavelength accuracy	± 1 nm, self-calibration with deuterium lines. Verification with holmium oxide filter,		
Wavelength bunching         Programmable, 1 - 400 nm, in steps of 1 nm           Flow cells         Standard 13-µL volume, 10 mm-cell path length, 120 bar (1740 psi) pressure maximum Semi-micro 5-µL volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum Micro 2-µL, volume, 3-mm cell path length, 120 bar (1740 psi) pressure maximum Semi-nano 500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum Micro 30-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum Mino 80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum Mino 80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum Preparative 3 mm 3-mm cell path length, 120 bar (1740 psi) pressure maximum Migh Pressure (tor SFC) 1.7-µL volume, 6-mm cell path length, 400 bar (5802 psi) pressure maximum Preparative 3 mm 0.3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz Preparative 0.06-mm 0.05-mm cell path length, 20 bar (291 psi) pressure maximum, quartz           Time programmable         Wavelength, polarity, peak width, lamp bandwidth, autobalance, wavelength range, threshold, spectra storage mode.           Analog output         Cacroder/integrator: 100 mV or 1 V. 2 outputs.         Communications         LAN. Controller-area network (CAN), RS-232C, APG Remote: ready. Start, stop and shut-down signals.         GLP features         Data recovery card to prevent data losses. RFID for electronics records of flow cell and UV lamp conditions (path length, volume, product number, serial number, test passed, usage)         Start stop and shut-down signals.           Safety and maintenance         Easty maintenance feedback messages. Electronic records of flow cell and UV lamp conditions (path length, volume, product number, serial number, t	Slit width	Programmable: 1, 2, 4, 8, 16 nm		
Flow cellsStandard 13-µL volume, 10 mm-cell path length, 120 bar (1740 psi) pressure maximum Semi-micro 5-µL volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum Semi-nano 500-nanoliter volume, 10-mm cell path length, 120 bar (1740 psi) pressure maximum Semi-nano 500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum Nano Bi-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum Nano Bi-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum Preparative 3 mm 0.3-mm cell path length, 120 bar (1740 psi) pressure maximum Preparative 3 mm 0.3-mm cell path length, 20 bar (291 psi) pressure maximum, quartzTime programmableWavelength, polarity, peak width, lamp bandwidth, autobalance, wavelength range, threshold, spectra storage mode.Analog outputRecorder/integrator: 100 mV or 1 V, 2 outputs.CommunicationsLAN, Controller-area network (CAN), RS-232C, APG Remote: ready, Start, stop and shut-down signals.GLP featuresData recovery card to prevent dal losses. RFID for electronics records of flow cell and UV lamp conditions (path length, volume, read and losses, RFID or electronics records of flow cell and UV lamp conditions (path length, could number, serial number, ter passed, usage) Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user satable limits and feedback messages. Electronic records of flow cell and UV lamp conditions (path length, accuracy with built-in holimin owide filter.Safety and maintenanceExtensive diagnostics, error detection and display through Agitent Instant Pilot and Agilent Lab Advisor software. Leak detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major	Diode width	< 1 nm		
13-pL volume, 10 mm-cell path length, 120 bar (1740 psi) pressure maximumSemi-nicro S-pL volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximumMicro 2-pL, volume, 3-mm cell path length, 120 bar (1740 psi) pressure maximumSemi-nano 500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximumNano 80-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximumNano 80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximumNano 80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximumPreparative 3 mm 3-mm cell path length, 120 bar (1740 psi) pressure maximumPreparative 3 mm 0.3-mm cell path length, 20 bar (291 psi) pressure maximum, quartzPreparative 3 mm 0.3-mm cell path length, 20 bar (291 psi) pressure maximum, quartzPreparative 3.06-mm cell path length, 20 bar (291 psi) pressure maximum, quartzPreparative 3.06-mm cell path length, 20 bar (291 psi) pressure maximum, quartzCommunicationsEcorder/integrator: 100 mV or 1 V.2 outputs.CommunicationsData recovery card to prevent data losses. RFID for electronics records of flow cell and UV lamp conditions (path length, audoelance, wavelength range, interns of lamp burn time with user satable limits and feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user satable limits and feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user satable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength accuracy with built-in holmium oxide filter.Safety and maintenanceErensive diagnostics, error detection and display through Agilent Instant Flot a	Wavelength bunching	Programmable, 1 - 400 nm, in steps of 1 nm		
Analog outputRecorder/integrator: 100 mV or 1 V, 2 outputs.CommunicationsLAN, Controller-area network (CAN), RS-232C, APG Remote: ready, Start, stop and shut-down signals.GLP featuresData recovery card to prevent data losses. RFID for electronics records of flow cell and UV lamp conditions (path length, volume, product number, serial number, test passed, usage) Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user settable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength accuracy with built-in holmium oxide filter.Safety and maintenanceExtensive diagnostics, error detection and display through Agilent Instant Pilot and Agilent Lab Advisor software. Leak detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major maintenance areas.	Flow cells	<ul> <li>13-μL volume, 10 mm-cell path length, 120 bar (1740 psi) pressure maximum</li> <li>Semi-micro</li> <li>5-μL volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum</li> <li>Micro</li> <li>2-μL, volume, 3-mm cell path length, 120 bar (1740 psi) pressure maximum</li> <li>Semi-nano</li> <li>500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum</li> <li>Nano</li> <li>80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum</li> <li>High Pressure (for SFC)</li> <li>1.7-μL volume, 6-mm cell path length, 400 bar (5802 psi) pressure maximum</li> <li>Preparative 3 mm</li> <li>3-mm cell path length, 120 bar (1740 psi) pressure maximum</li> <li>Preparative 3 mm</li> <li>0.3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz</li> <li>Preparative 0.06 mm</li> </ul>		
CommunicationsLAN, Controller-area network (CAN), RS-232C, APG Remote: ready, Start, stop and shut-down signals.GLP featuresData recovery card to prevent data losses. RFID for electronics records of flow cell and UV lamp conditions (path length, volume, product number, serial number, test passed, usage) Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user settable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength accuracy with built-in holmium oxide filter.Safety and maintenanceExtensive diagnostics, error detection and display through Agilent Instant Pilot and Agilent Lab Advisor software. Leak detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major maintenance areas.	Time programmable	Wavelength, polarity, peak width, lamp bandwidth, autobalance, wavelength range, threshold, spectra storage mode.		
GLP features       Data recovery card to prevent data losses. RFID for electronics records of flow cell and UV lamp conditions (path length, volume, product number, serial number, test passed, usage)         Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user settable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength accuracy with built-in holmium oxide filter.         Safety and maintenance       Extensive diagnostics, error detection and display through Agilent Instant Pilot and Agilent Lab Advisor software. Leak detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major maintenance areas.	Analog output	Recorder/integrator: 100 mV or 1 V, 2 outputs.		
volume, product number, serial number, test passed, usage)Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user settable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength accuracy with built-in holmium oxide filter.Safety and maintenanceExtensive diagnostics, error detection and display through Agilent Instant Pilot and Agilent Lab Advisor software. Leak detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major maintenance areas.	Communications	LAN, Controller-area network (CAN), RS-232C, APG Remote: ready, Start, stop and shut-down signals.		
detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major maintenance areas.	GLP features	volume, product number, serial number, test passed, usage) Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user settable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength		
Others Electronic temperature control (ETC) for the complete optical unit.	Safety and maintenance	detection, safe leak handling, and leak output signal for shutdown of pumping system. Low voltages in major		
	Others	Electronic temperature control (ETC) for the complete optical unit.		

Specifications: 1260 Infinity Multiple Specification (1997)	ple Wavelength Detector VL (G1365D)		
Detector type	1024-element diode array		
Light source	Deuterium and tungsten		
Number of signals	8		
Maximum sampling rate	20 Hz		
Short-term noise	$<\pm$ 0.7 x 10 $^{5}$ AU at 254/4 nm and at 750 nm, TC 2 sec.		
Drift	< 0.9 x 10 <sup>-3</sup> AU/hr at 254 nm		
Linearity	> 2.0 AU (5 %) at 265 nm		
Wavelength range	190-950 nm		
Wavelength accuracy	$\pm$ 1 nm, self-calibration with deuterium lines verification with holmium oxide filter.		
Slit width	Programmable: 1, 2, 4, 8, 16 nm		
Diode width	< 1 nm		
Wavelength bunching	Programmable, a - 400 nm, in steps of 1 nm		
Flow cells	Standard         13-μL volume, 10 mm-cell path length, 120 bar (1740 psi) pressure maximum         Semi-micro         5-μL volume, 6-mm cell path length, 120 bar (1740 psi) pressure maximum         Micro         2-μL, volume, 3-mm cell path length, 120 bar (1740 psi) pressure maximum         Semi-nano         500-nanoliter volume, 10-mm cell path length, 50 bar (725 psi) pressure maximum         Nano         80-nanoliter volume, 6-mm cell path length, 50 bar (725 psi) pressure maximum         High Pressure (for SFC)         1.7-μL volume, 6-mm cell path length, 400 bar (5802 psi) pressure maximum         Preparative 3 mm         3-mm cell path length, 120 bar (1740 psi) pressure maximum         Preparative 3 mm         0.3-mm cell path length, 20 bar (291 psi) pressure maximum, quartz         Preparative 0.06 mm         0.06-mm cell path length, 20 bar (291 psi) pressure maximum, quartz		
Time programmable	Wavelength, polarity, peak width, lamp bandwidth, autobalance, wavelength range, threshold, spectra storage mode.		
Analog output	Recorder/integrator: 100 mV or 1 V, 2 outputs		
Communications	LAN, Controller-area network (CAN), RS-232C, APG Remote: ready start, stop and shut-down signals,		
GLP features	RFID for electronics records of flow cell and UV lamp conditions (path length, volume, product number, serial number, test passed, usage) Early maintenance feedback (EMF) for continuous tracking of instrument usage in terms of lamp burn time with user settable limits and feedback messages. Electronic records of maintenance and errors. Verification of wavelength accuracy with built-in holmium oxide filter.		
Safety and maintenance	Extensive diagnostics, error detection and display through Agilent Instant Pilot and Agilent Lab Advisor software. Leak detection, safe leak handling, leak output signal for shutdown of pumping system. Low voltages in major maintenance		
	areas.		

### **Orderig Details – Agilent 1260 Infinity Multiple Wavelength Detector**

Description	Product Number
Agilent 1260 Infinity Multiple Wavelength Detector Includes CAN cable and LAN interface with cable. Must order one flow cell.	G1365C
<b>Micro flow cell</b> 2 μL volume, 3 mm path length, 120 bar pressure limit.	#010
Nano flow cell 80 nLvolume, 6 mm path length, 50 bar pressure limit.	#012
<b>Semi-nano flow cell</b> 500 nL volume, 10 mm path length, 50 bar pressure limit.	#014
<b>Semi-micro flow cell</b> 5 μL volume, 6 mm path length, 120 bar pressure limit.	#016
<b>Standard flow cell</b> 13 μL volume, 10 mm path length, 120 bar pressure limit.	#018
<b>Micro, high-pressure flow cell (for SFC)</b> 1.7 μL volume, 6-mm path length, 400 bar pressure limit.	#020
<b>Preparative flow cell 3 mm</b> 4 μL volume, 3 mm path length, 120 bar pressure limit.	#022
Preparative flow cell 0.3 mm 0,3 mm path length, 20 bar, pressure limit.	#024
Preparative flow cell 0.06 mm 0,06 mm path length, 20 bar, pressure limit.	#026

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